

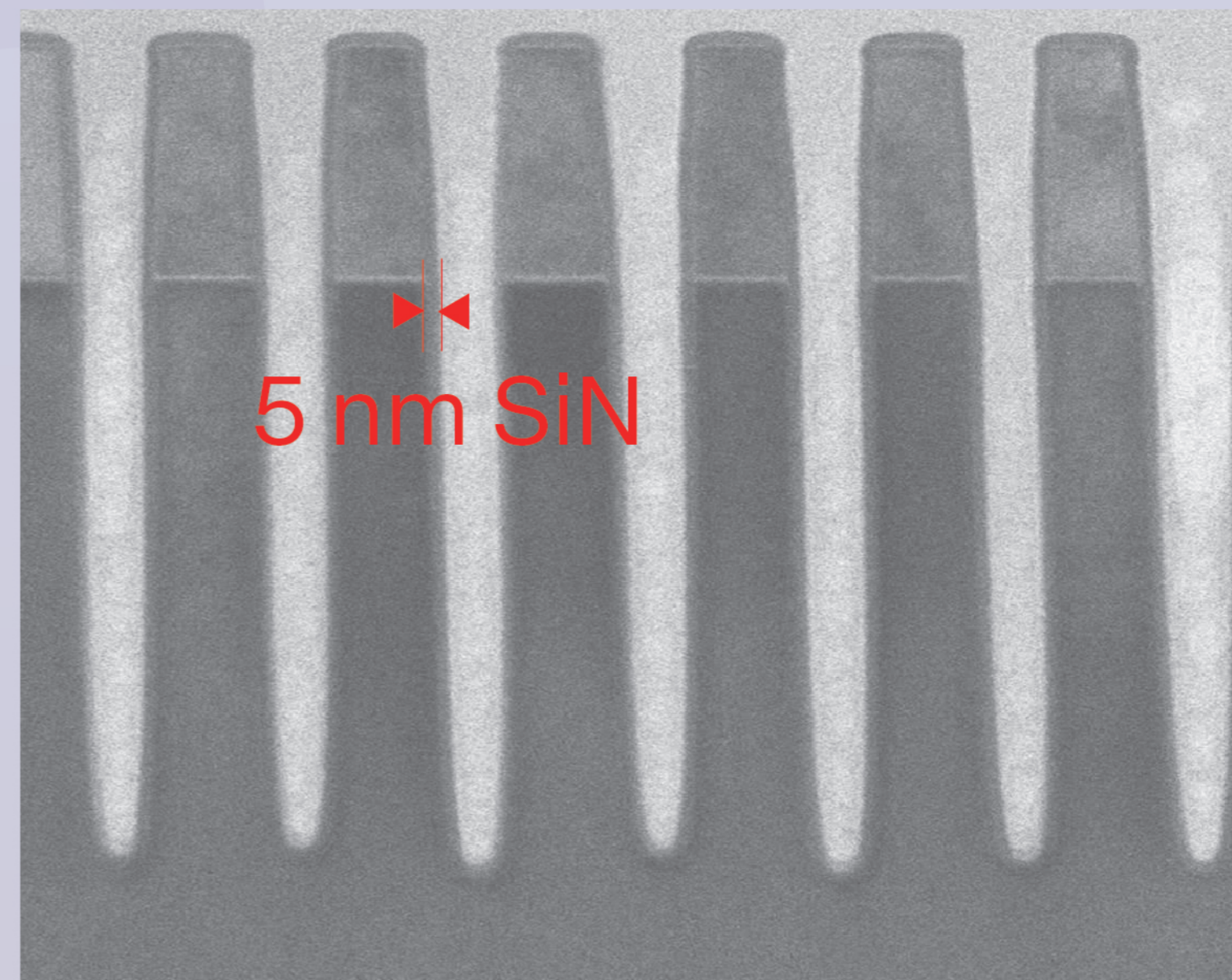
ALD/CVD Precursors

(Yamanaka Hutech Corporation)



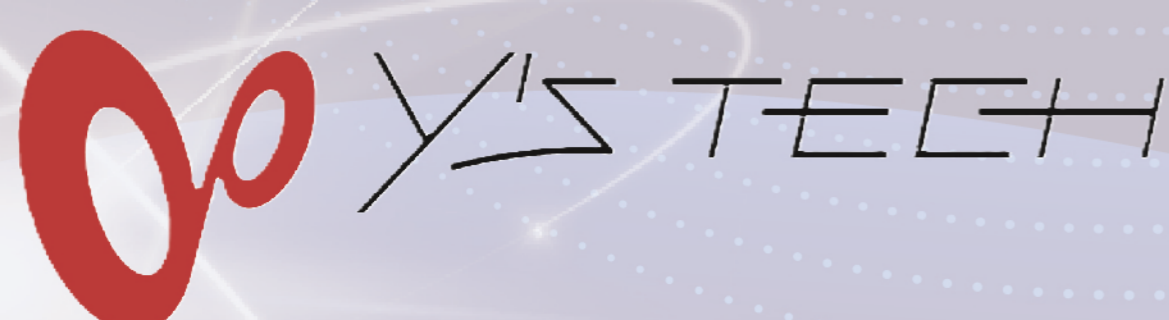
For over 50 years, Yamanaka Hutech has been a trusted supplier of high-purity chemicals essential for wafer deposition and doping processes in semiconductor manufacturing. As of August 1, 2024, Yamanaka Hutech has officially joined JSR Group.

Yamanaka Hutech offers a comprehensive lineup of film-forming materials for semiconductors, including lineup of ALD/CVD precursors for SiO and SiN deposition



Conformal deposition film by PEALD

Category	Chemical		CAS#
CVD/ALD Precursor	TEOS	Tetraethoxysilane	78-10-4
	BDEAS	Bis(dimethylamino)dimethylsilane	27804-64-4
	OMCTS	Octamethylcyclotetrasiloxane	556-67-2
	DMDMOS	Dimethyldimethoxysilane	1112-39-6
	4MS	Tetramethylsilane	75-76-3
	HMDSO	Hexamethyldisiloxane	107-46-0
	HMDSN	Hexamethyldisilazane	999-97-3
Dopant	POCl ₃	Phosphorus trichloride	7719-12-2
	BBr ₃	Boron tribromide	10294-33-4
	As	Arsenic	7440-38-2
	P	Phosphorus	7723-14-0
	TEPO	Triethyl phosphate	78-40-0
	TMPO	Trimethyl phosphate	512-56-1
	TEB	Triethyl borate	150-46-9
Compound Semiconductor	TMB	Trimethyl borate	121-43-7
	GaCl ₃	Gallium trichloride	1345-90-3
	Ga ₂ O ₃	Gallium oxide	12024-21-4
Solar Cell Field	POCl ₃	Phosphorus trichloride	7719-12-2



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